
Analysis of Organic Additives in CMP Slurry

Toray Research Center, Inc.
Organic Analysis Laboratory

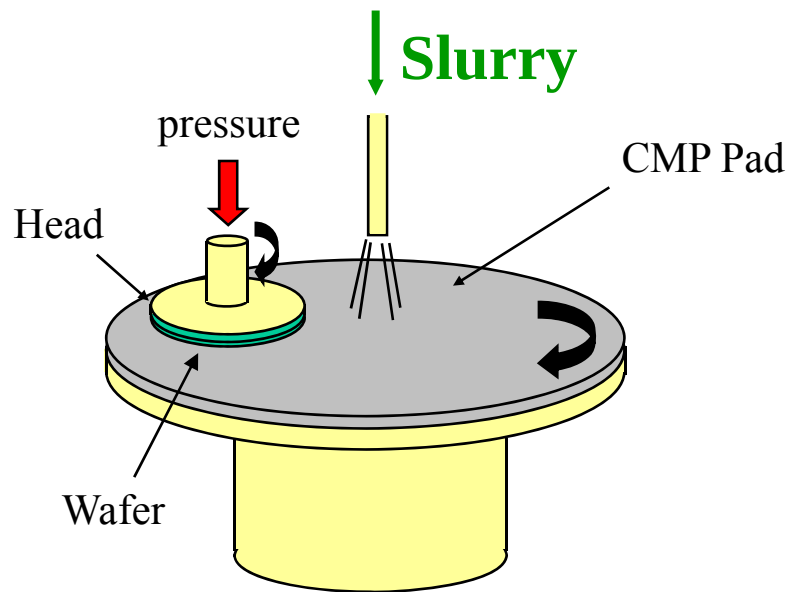


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CMP Slurry

CMP = Chemical Mechanical Polishing



Chemical

← Additives

Mechanical

← Particles, Pad

<Typical Composition of Slurry>

Particles

Silica, Almina, Ceria etc.

Additives

- Dispersant : Polyethylene glycol(PEG) etc.
- Chelating Agent :
Lactic acid, Quinaldinic acid
- Corrosion Inhibitor : Benzotriazole
- Alcohol : Isopropanol
- pH conditioner :
Inorganic acid , Ammonium etc.
- Oxidizing Agent : H_2O_2



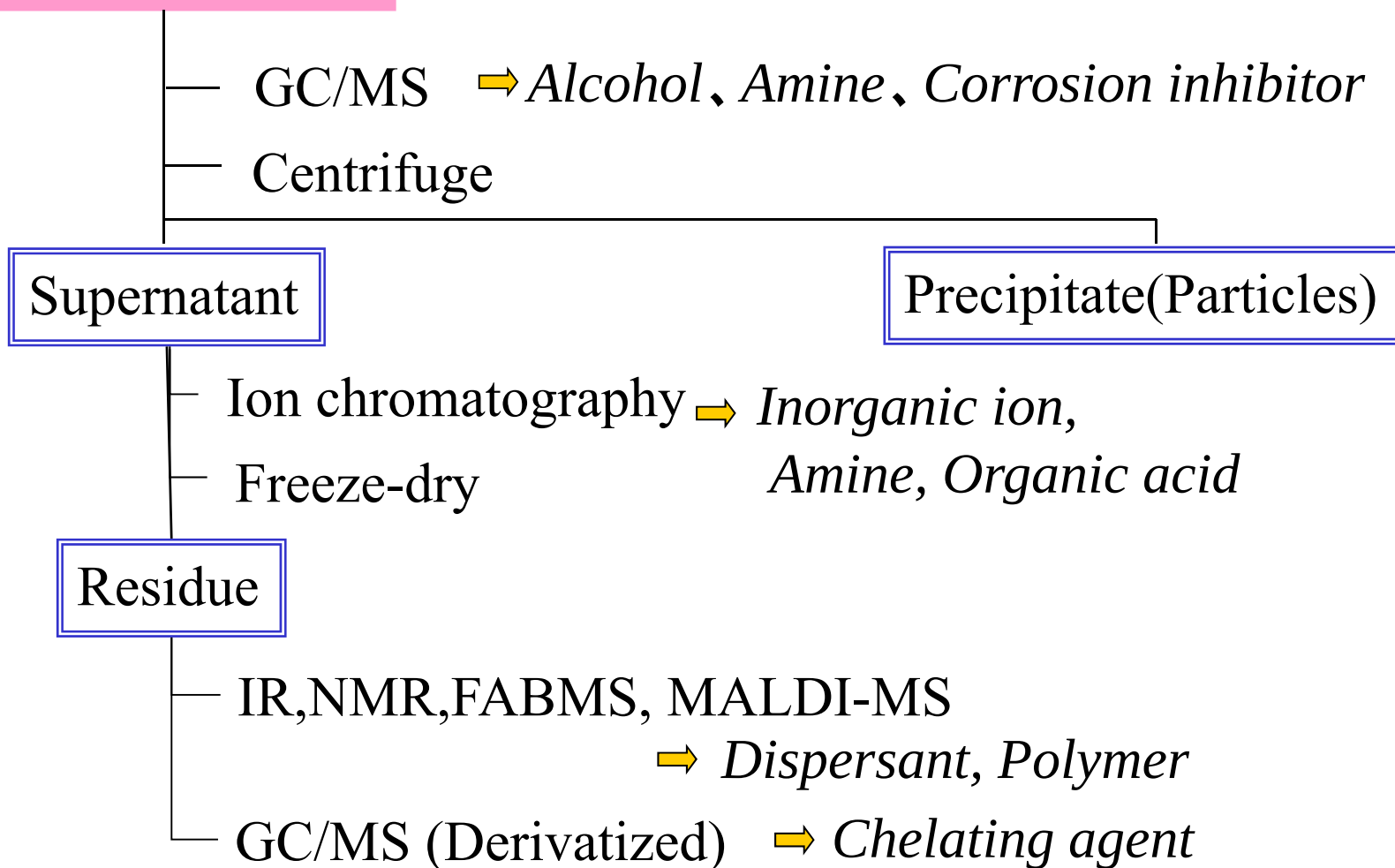
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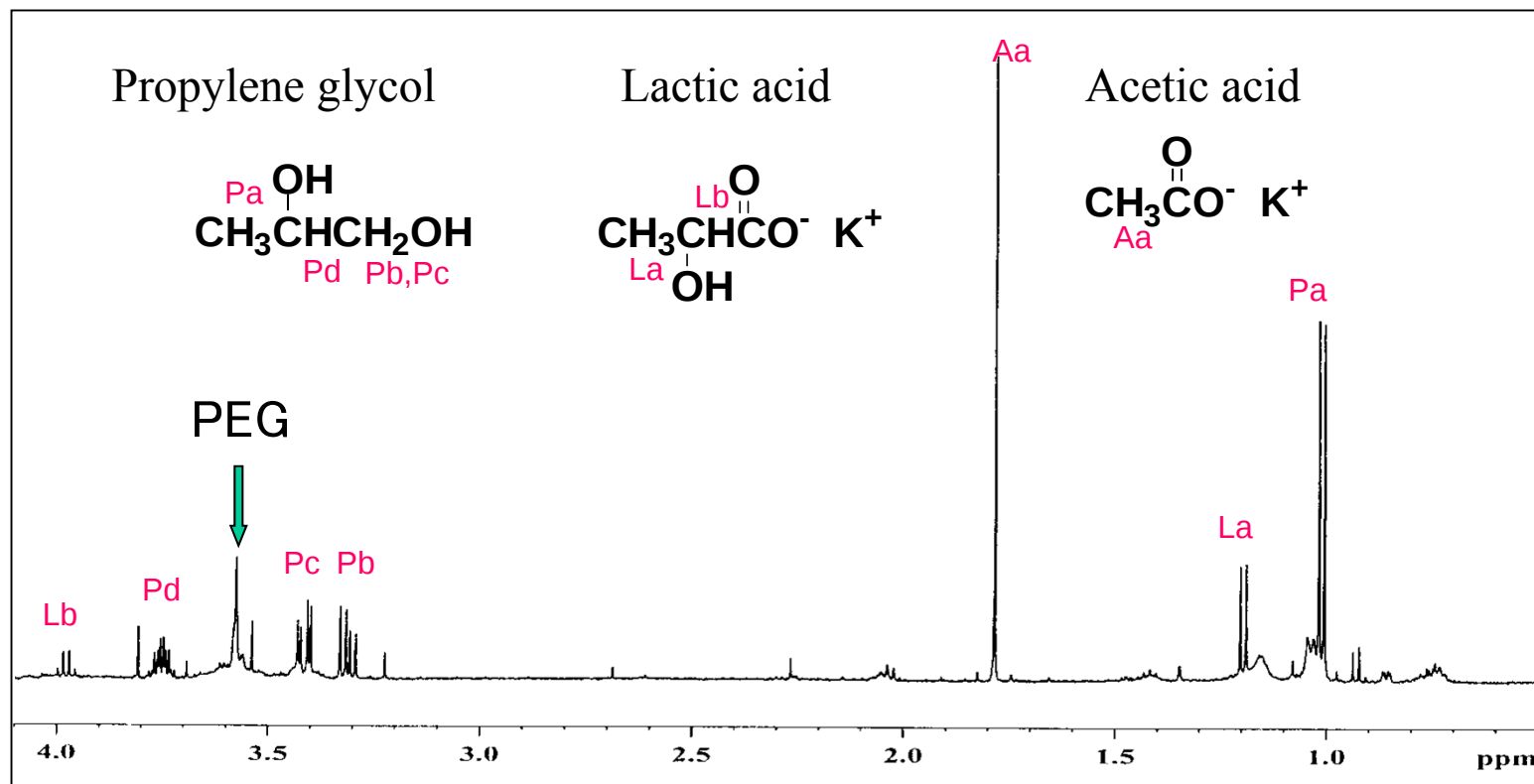
Composition analysis of CMP slurry

CMP slurry

Analytical Method



^1H -NMR spectrum of Additives in Residue



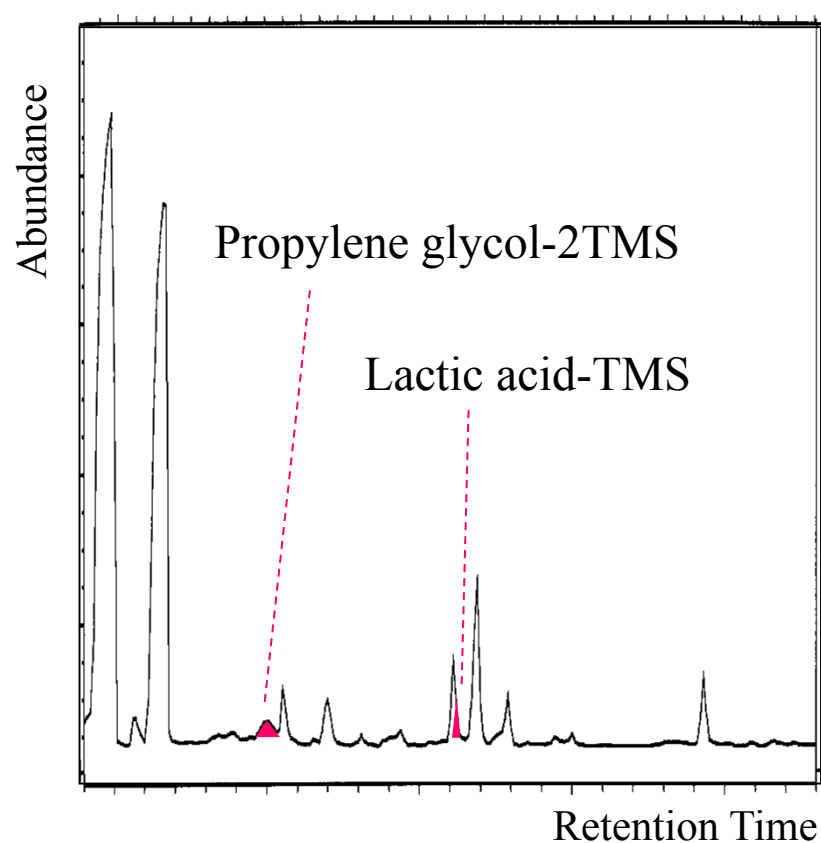
Trace amount of dispersant and chelating agent were detected from the ^1H -NMR spectrum.



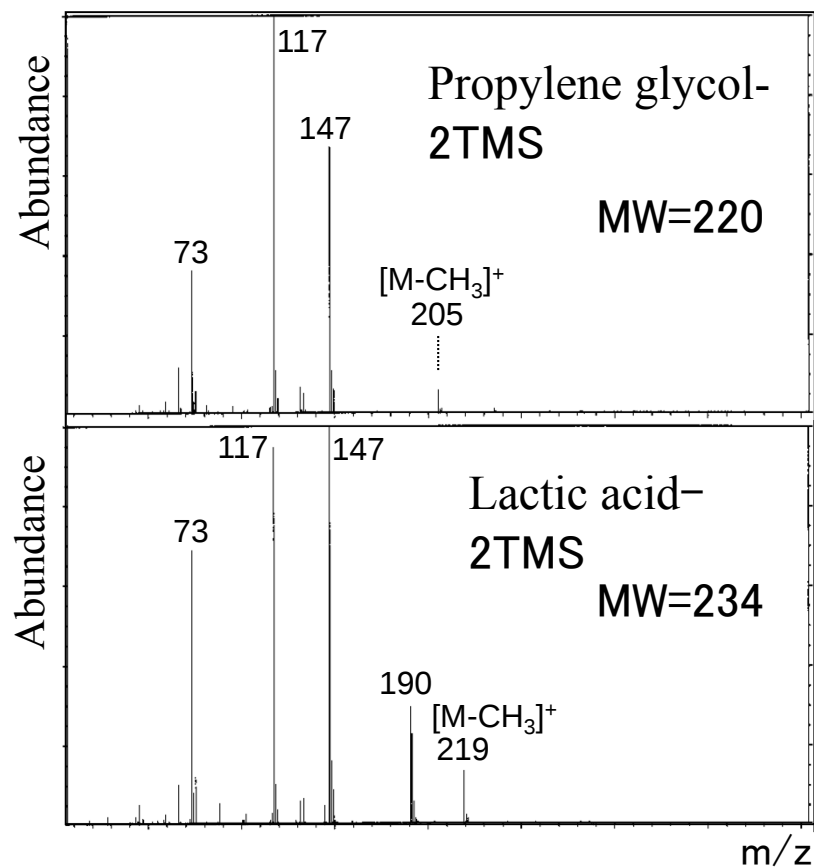
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GC/MS analysis of Derivatized Additives in Residue



Total Ion Chromatogram



Mass Spectra

Polar compounds such as the chelating agents were determined by GC/MS analysis of Trimethylsilyl(TMS) derivatives of residue.

